

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	287	(electron\$1 adj20 beam\$1) and ((sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5) adj30 (chamber\$1 or housing\$1)) and (gas\$5 adj30 (chamber\$1 or housing\$1)) and ((neutraliz\$5 or reduc\$5 or eliminat\$5) adj30 charg\$5 adj30 (sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2009/01/16 13:55
L2	93	(electron\$1 adj20 beam\$1) and ((sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5) adj30 (chamber\$1 or housing\$1)) and (gas\$5 adj30 (chamber\$1 or housing\$1)) and ((neutraliz\$5 or reduc\$5 or eliminat\$5) adj30 charg\$5 adj30 (sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2009/01/16 13:58

		circuit\$5)) and (gas\$5 adj20 inlet \$5)				
L3	63	(electron\$1 adj20 beam\$1) and ((sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5) adj30 (chamber\$1 or housing\$1)) and (gas\$5 adj30 (chamber\$1 or housing\$1)) and ((neutraliz\$5 or reduc\$5 or eliminat\$5) adj30 charg\$5 adj30 (sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5)) and (gas\$5 adj20 inlet \$5) and (pressur \$5 adj20 gas\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2009/01/16 13:59
L4	30	(electron\$1 adj20 beam\$1) and ((sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5) adj30 (chamber\$1 or housing\$1)) and (gas\$5 adj30 (chamber\$1 or housing\$1)) and ((neutraliz\$5 or reduc\$5 or eliminat\$5) adj30 charg\$5 adj30 (sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2009/01/16 14:02

		circuit\$5)) and (gas\$5 adj20 inlet \$5) and (pressur \$5 adj20 gas\$5) and (secondary adj20 (electron\$1 or particle\$1))				
L5	1	((electron\$1 adj20 beam\$1) and ((sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5) adj30 (chamber\$1 or housing\$1)) and (gas\$5 adj30 (chamber\$1 or housing\$1)) and ((neutraliz\$5 or reduc\$5 or eliminat\$5) adj30 charg\$5 adj30 (sample\$1 or specimen\$1 or wafer\$1 or semiconduct\$5 or substrate\$1 or circuit\$5)) and (gas\$5 adj20 inlet \$5) and (pressur \$5 adj20 gas\$5) and (secondary adj20 (electron\$1 or particle\$1))). clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2009/01/16 14:41

1/16/09 2:46:45 PM

C:\Documents and Settings\KNguyen2\My Documents\EAST\Workspaces\default.
wsp